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Environment-dependent metastability of passivation-free indium zinc oxide thin film transistor after gate bias stress

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#	Paper	IF	Citations
191	High mobility and low operating voltage ZnGaO and ZnGaLiO transistors with spin-coated Al2O3as gate dielectric. <i>Journal Physics D: Applied Physics</i> , 2010 , 43, 442001	3	14
190	69.3: Amorphous Oxide TFT Backplane for Large Size AMOLED TVs. <i>Digest of Technical Papers SID International Symposium</i> , 2010 , 41, 1037	0.5	54
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	104		6.7	31
	103			12

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